

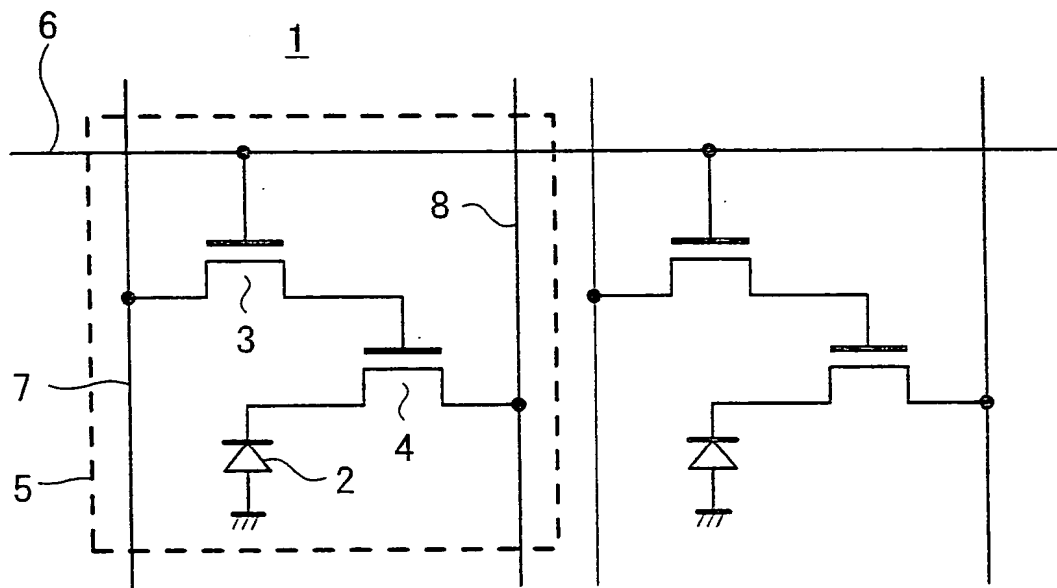
FIG. 1

FIG. 2

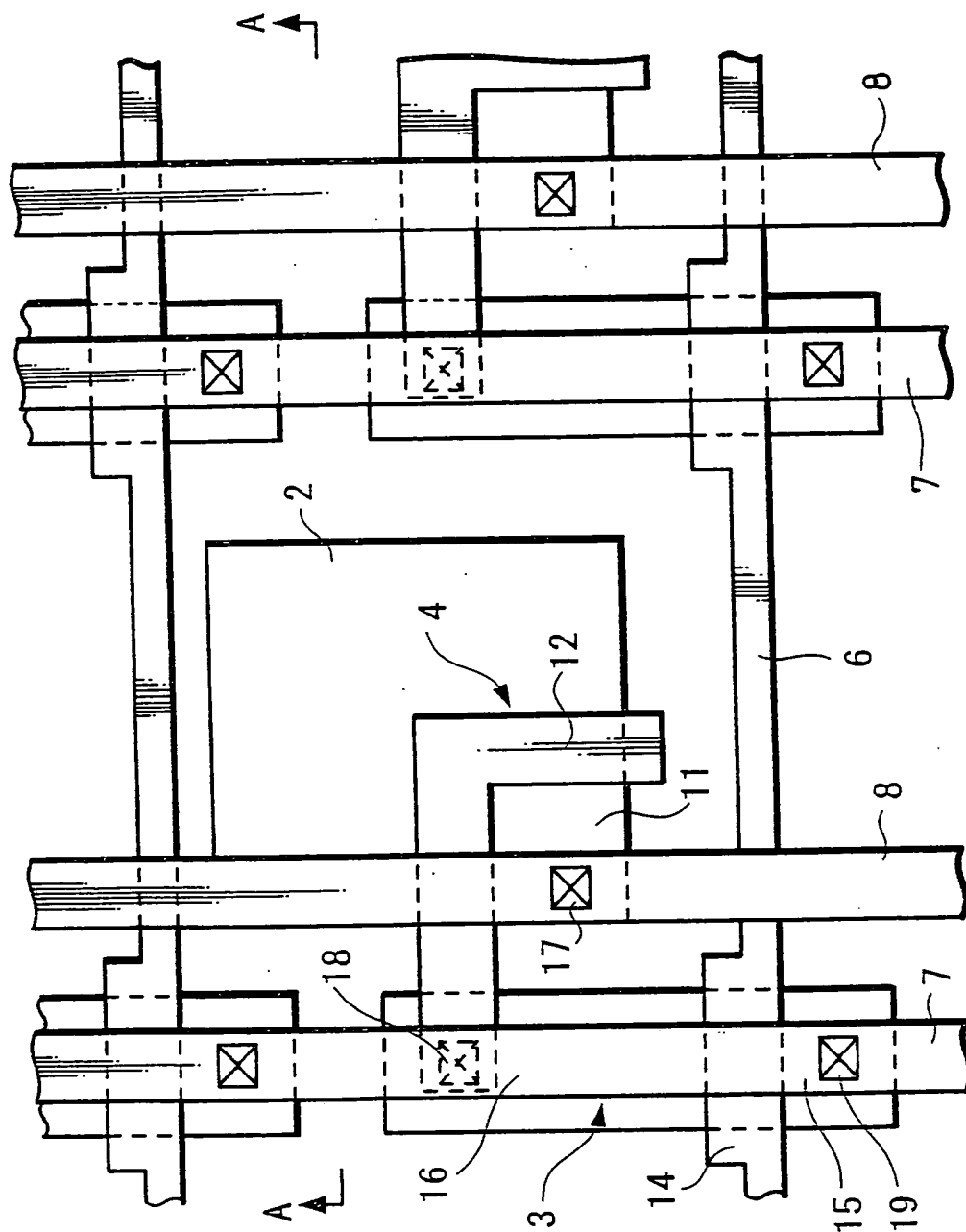


FIG. 3

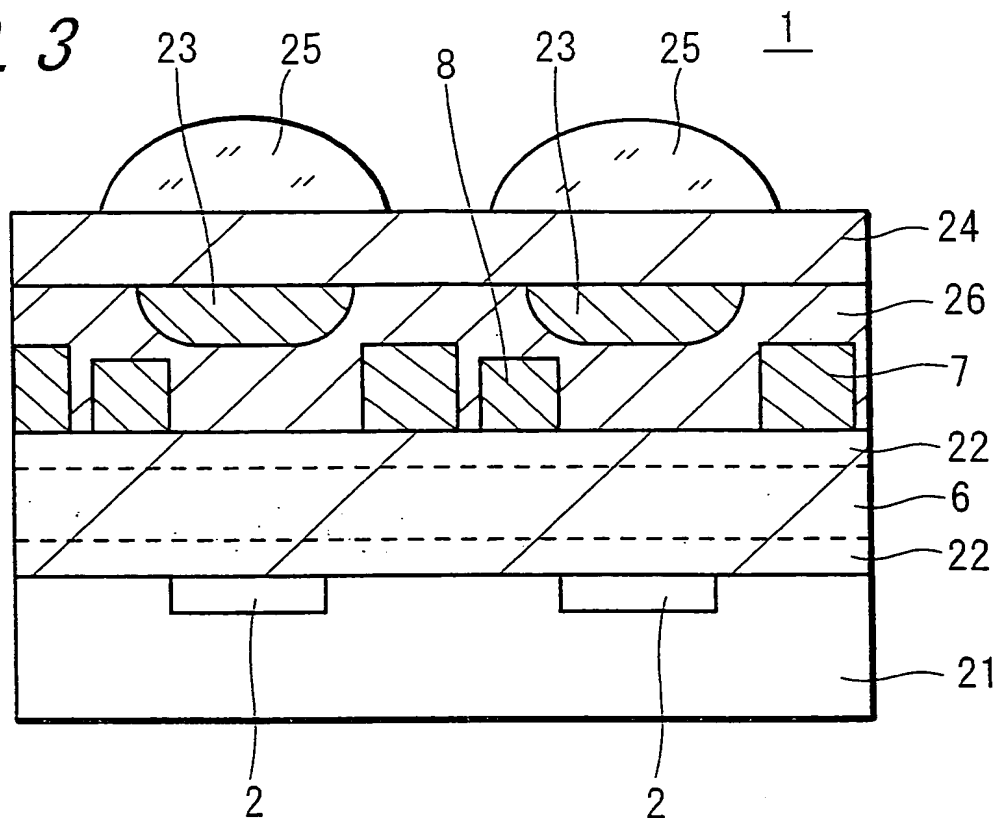


FIG. 4

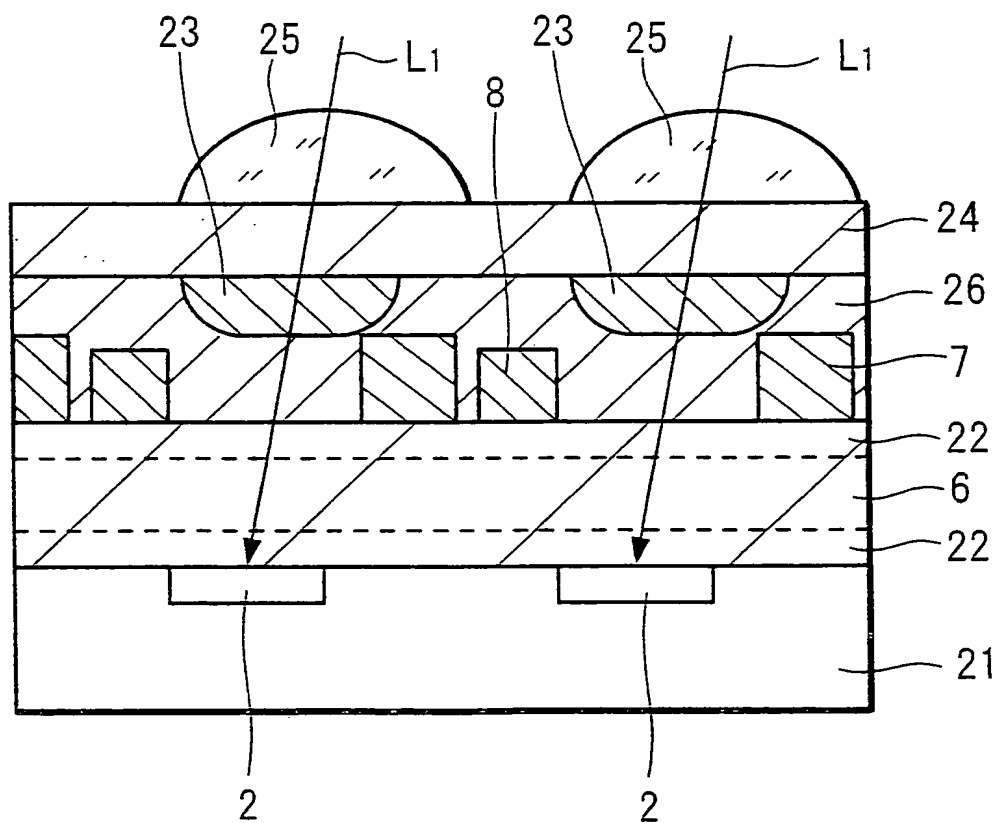


FIG. 5A

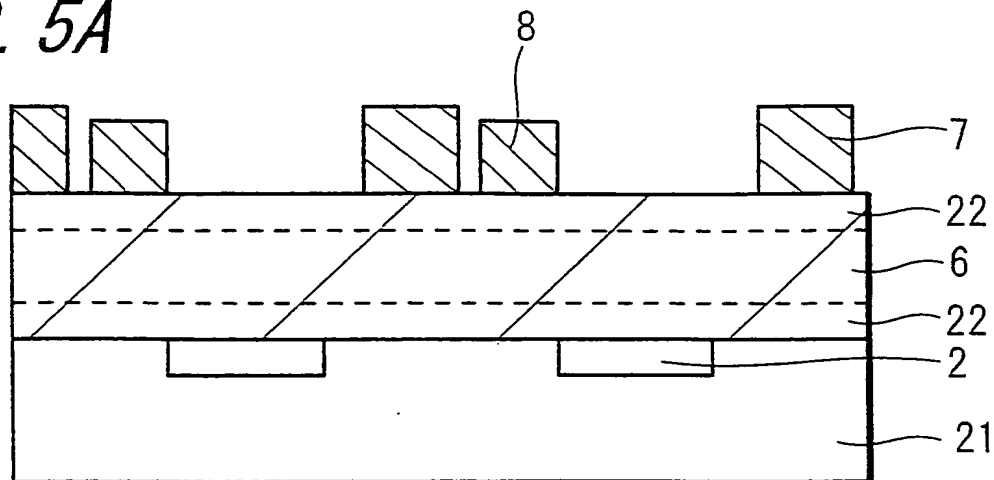


FIG. 5B

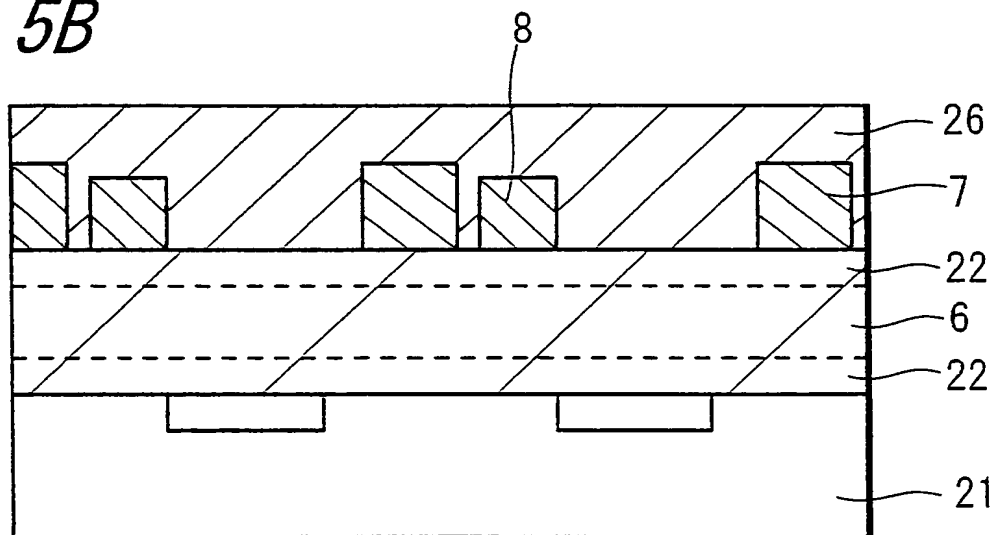


FIG. 5C

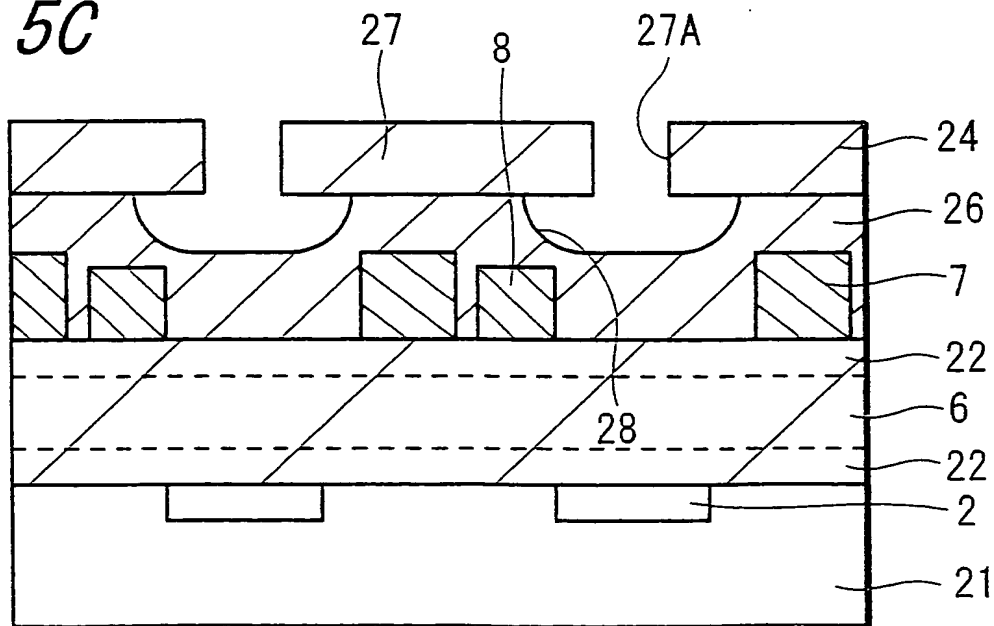


FIG. 6A

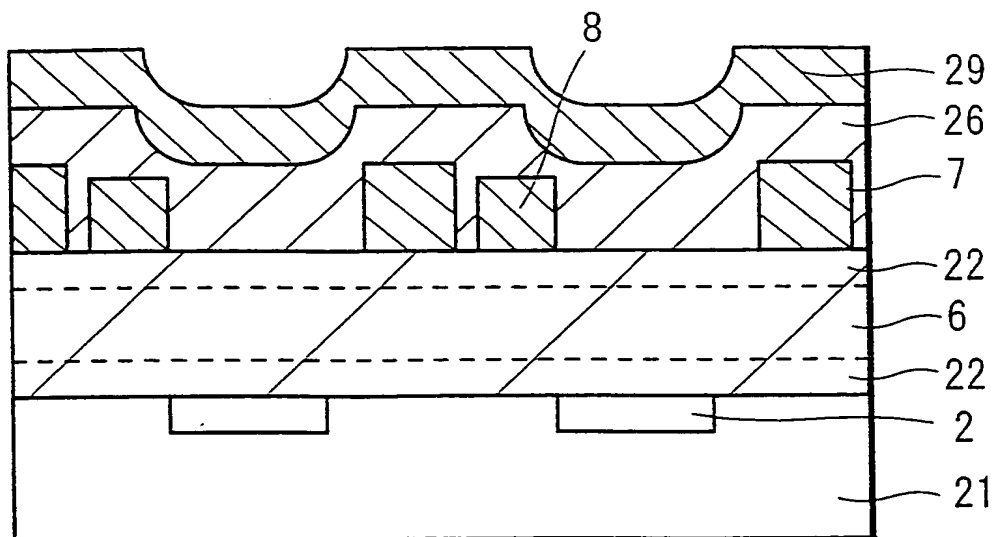


FIG. 6B

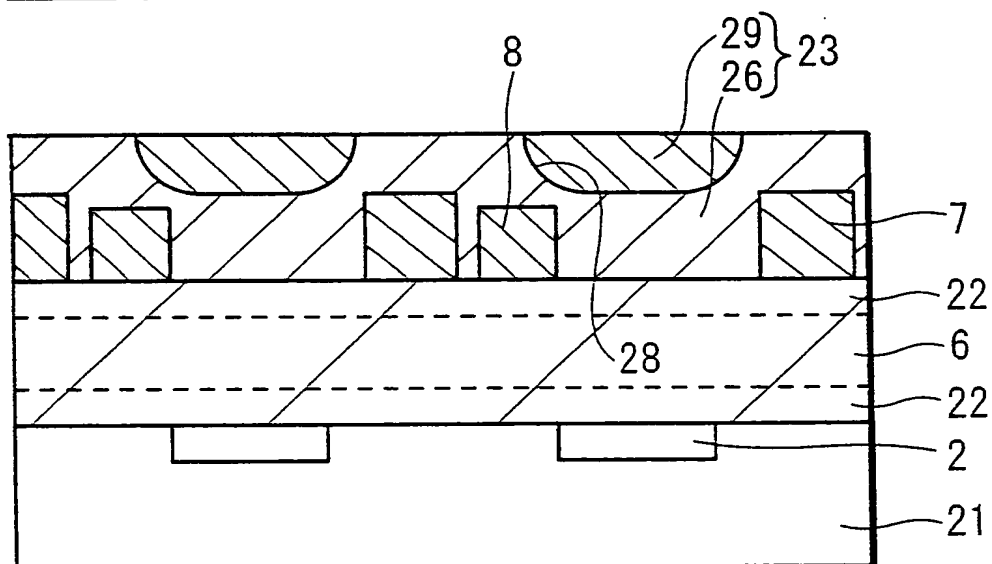


FIG. 6C

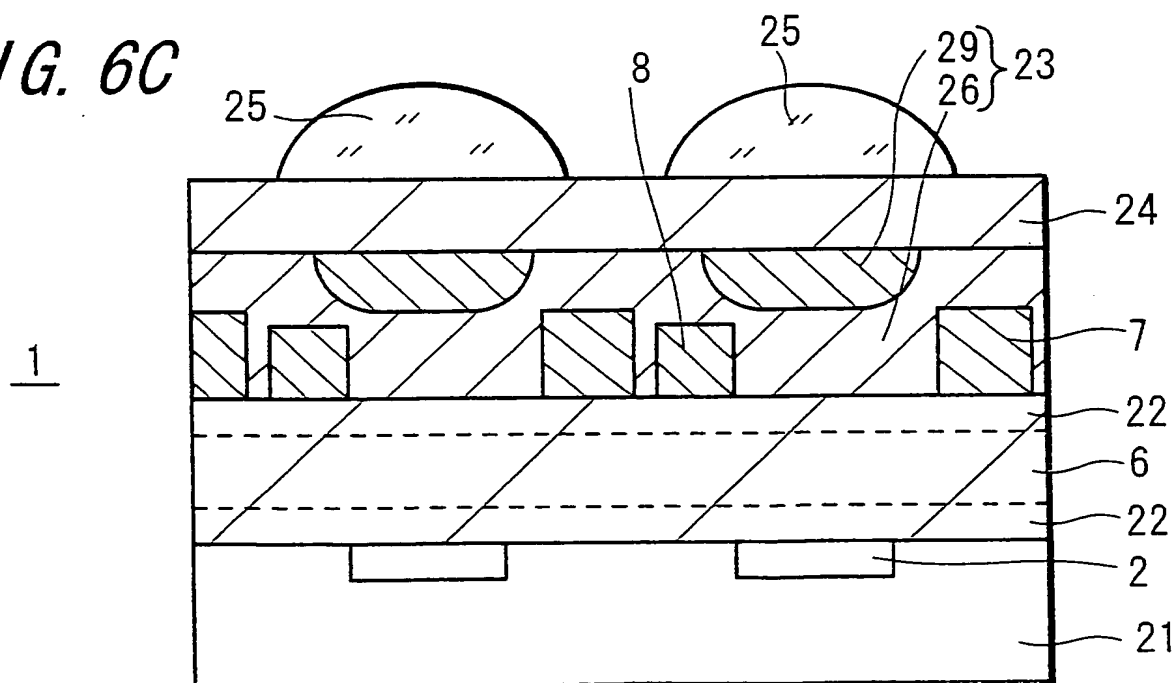


FIG. 7A

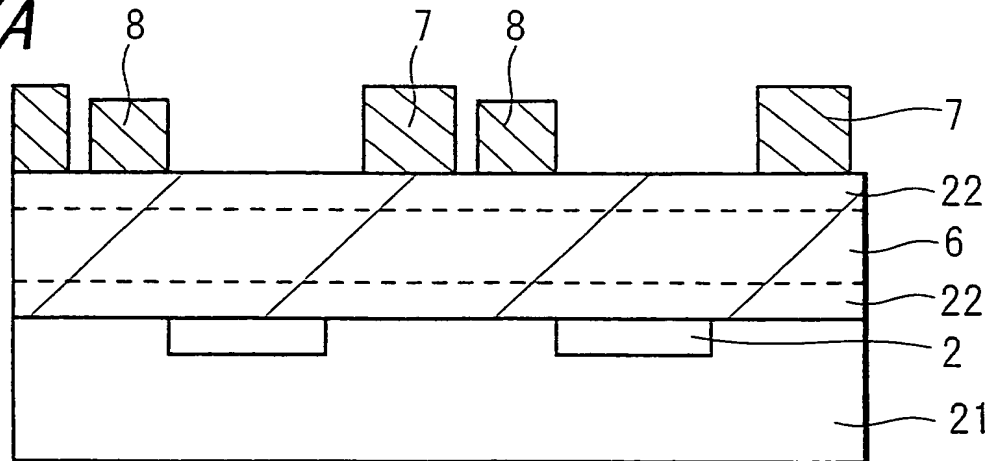


FIG. 7B

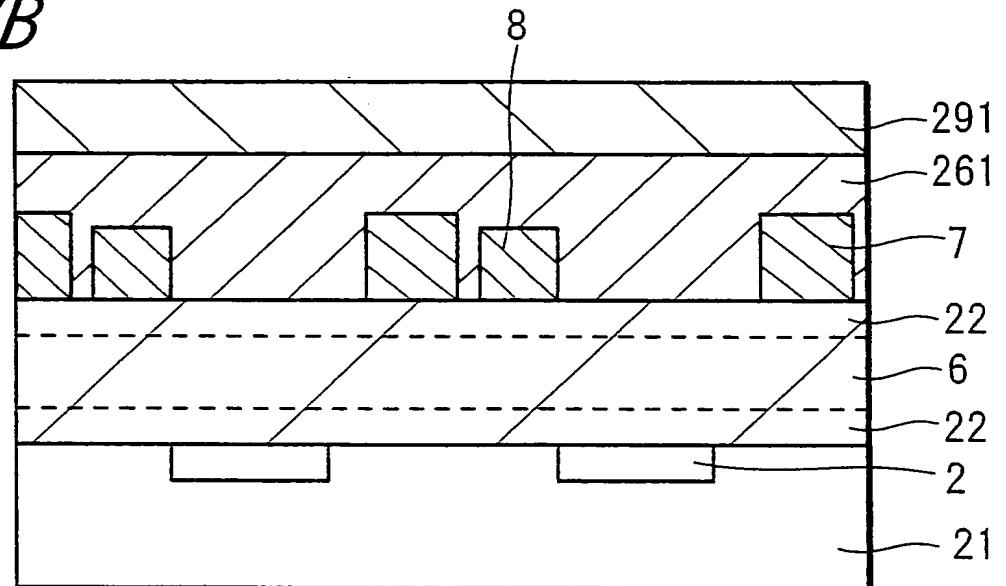


FIG. 7C

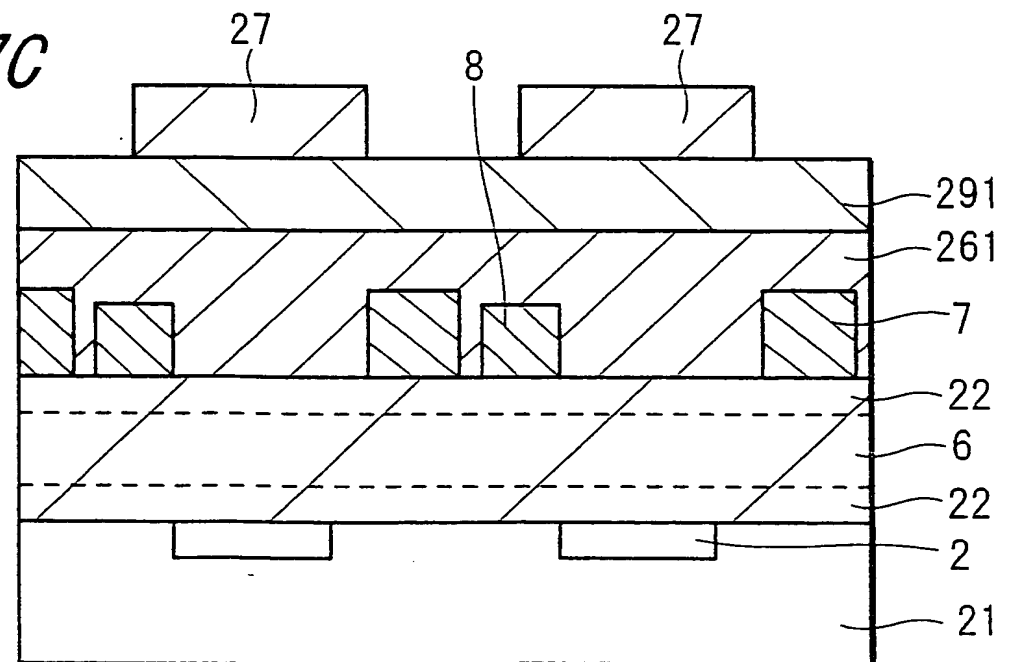


FIG. 8A

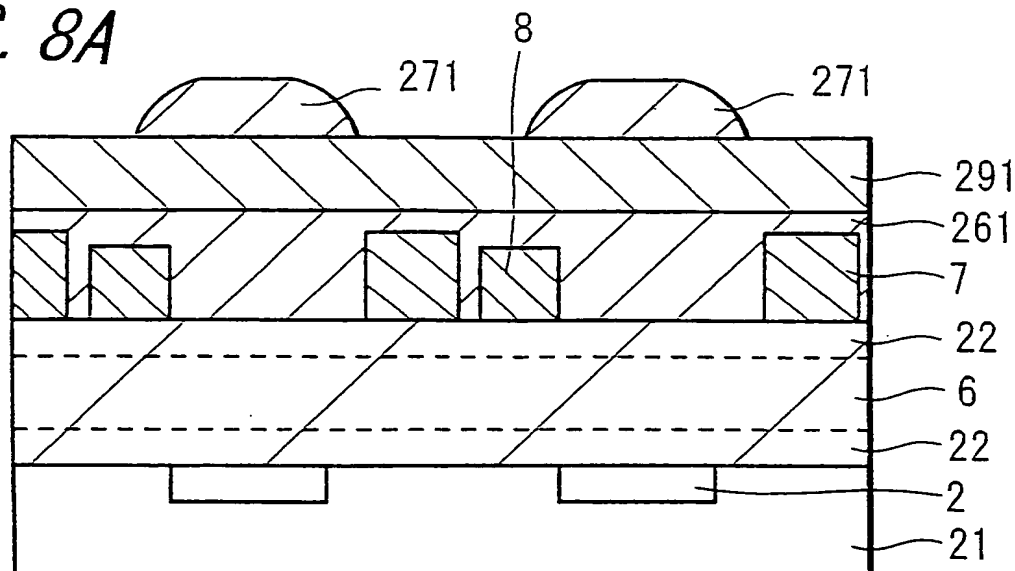


FIG. 8B

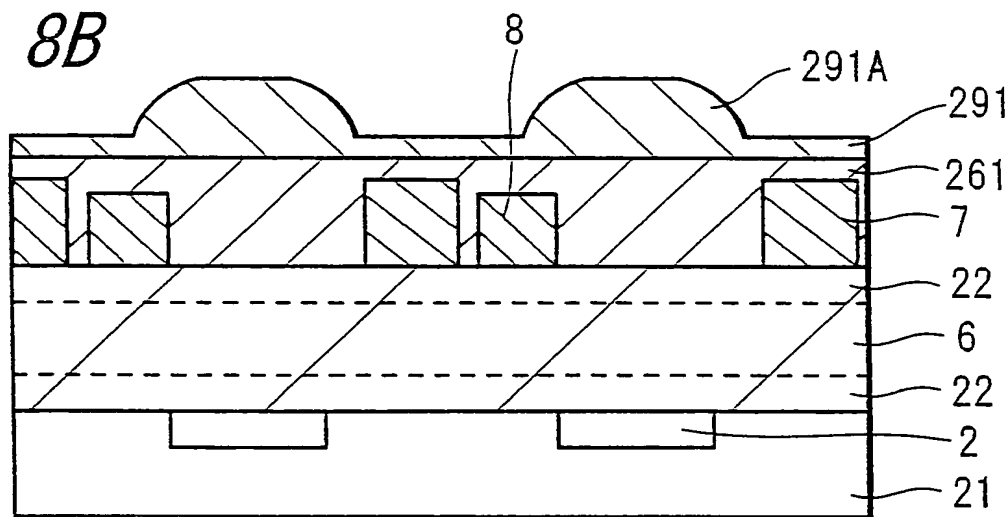


FIG. 8C

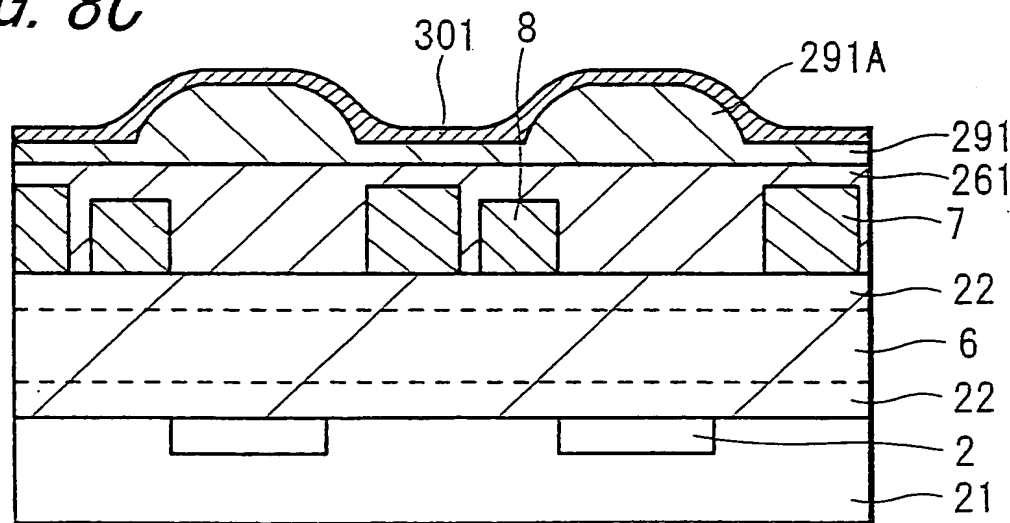


FIG. 9A

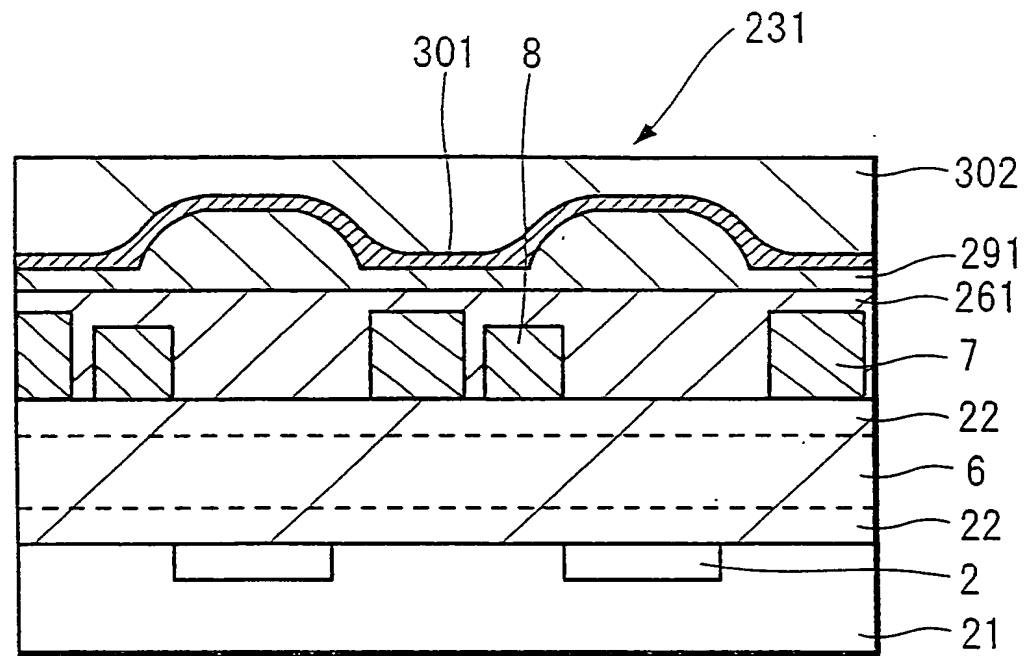


FIG. 9B

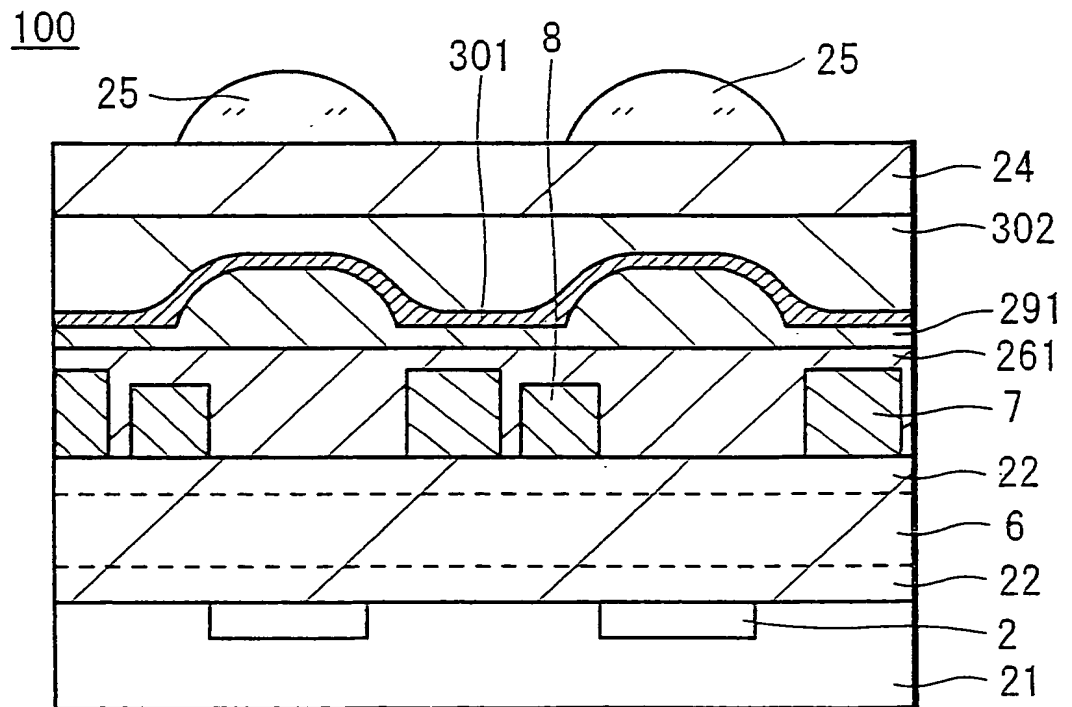


FIG. 10

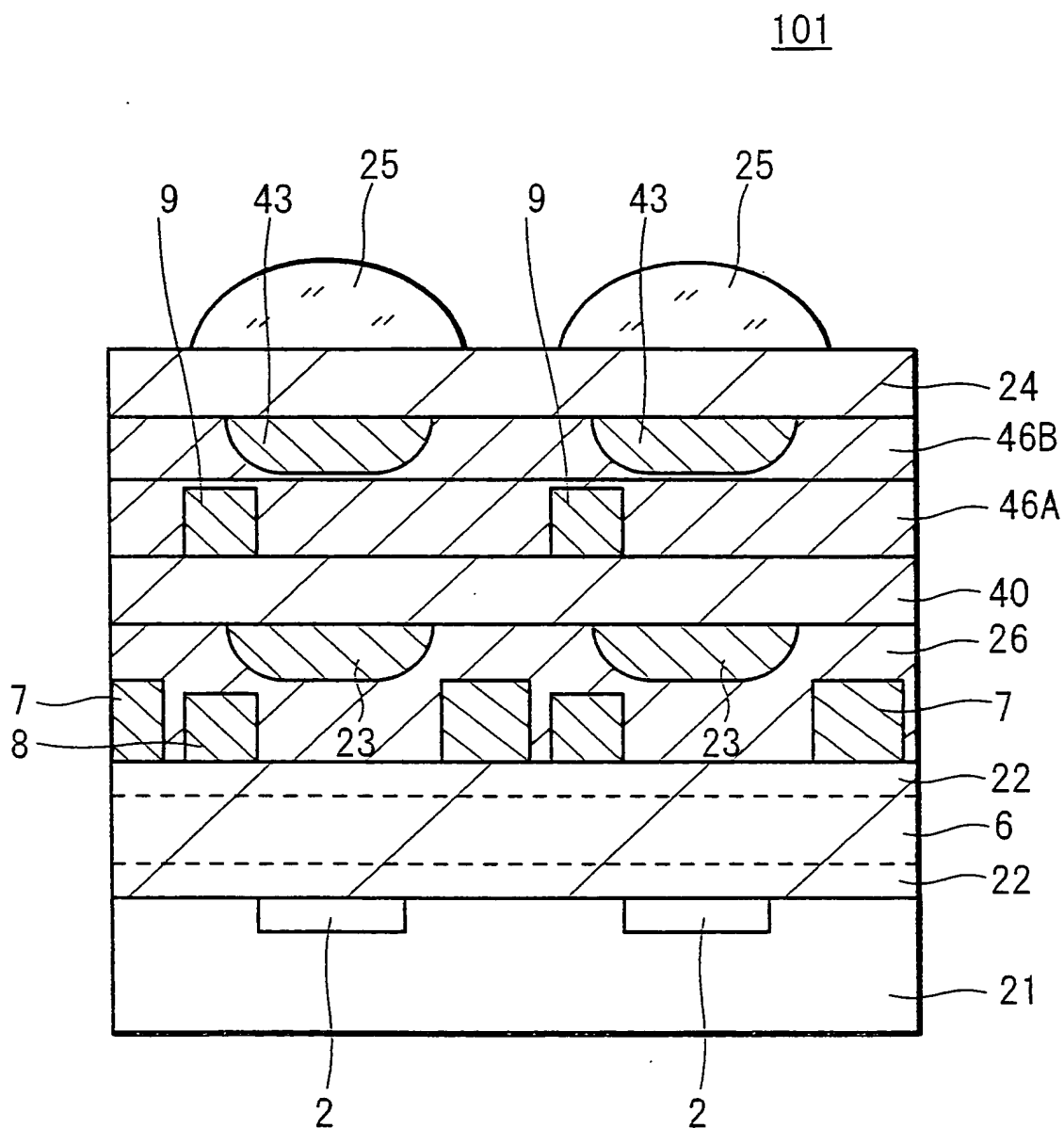


FIG. 11A

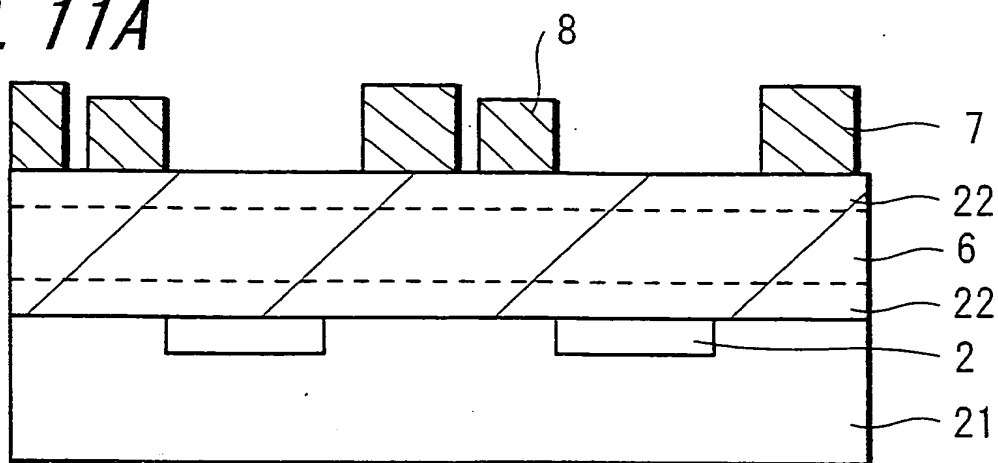


FIG. 11B

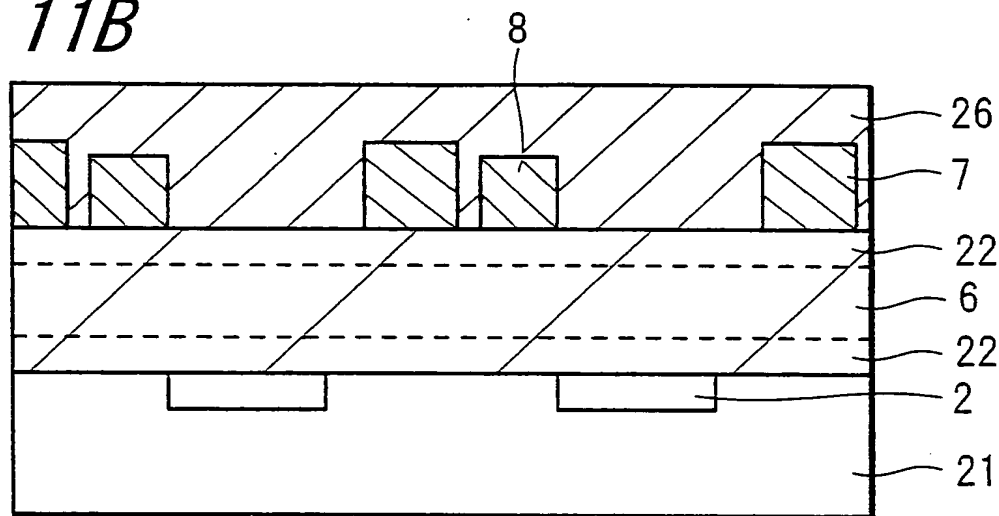


FIG. 11C

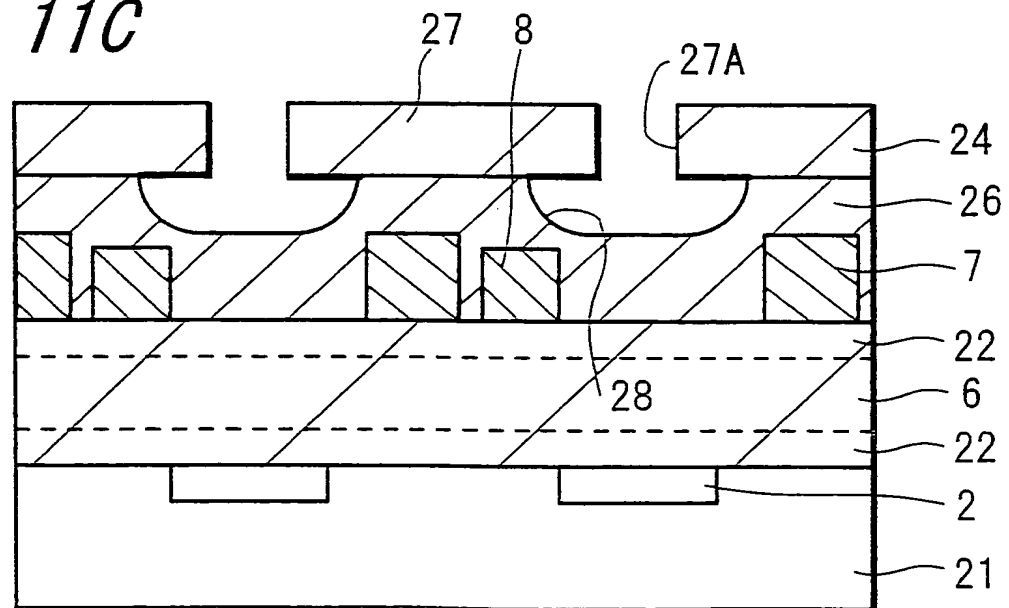


FIG. 12A

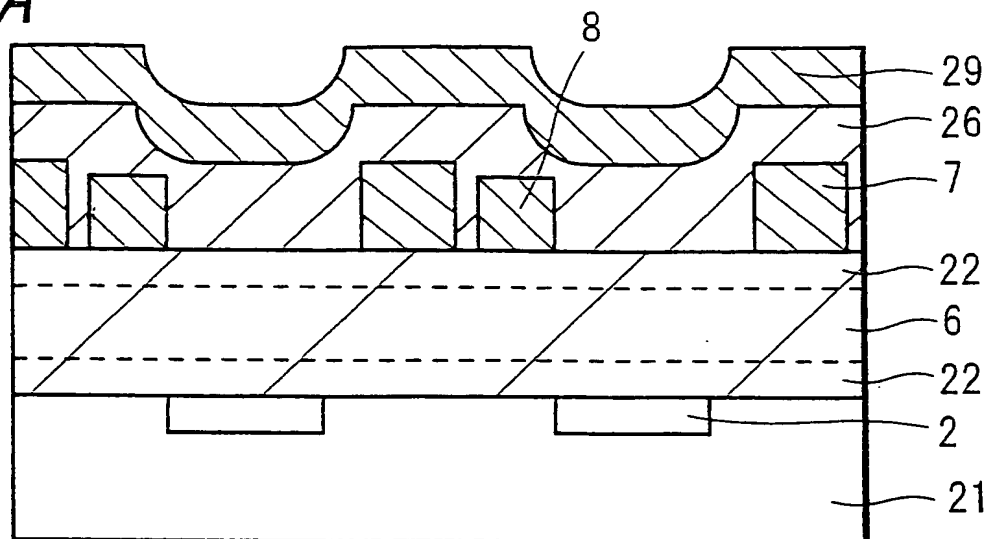


FIG. 12B

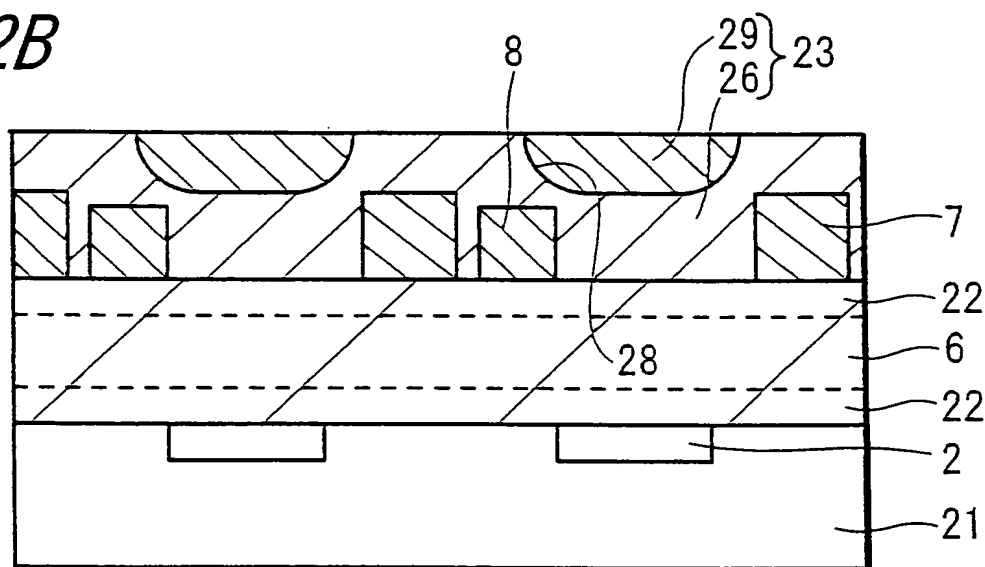


FIG. 12C

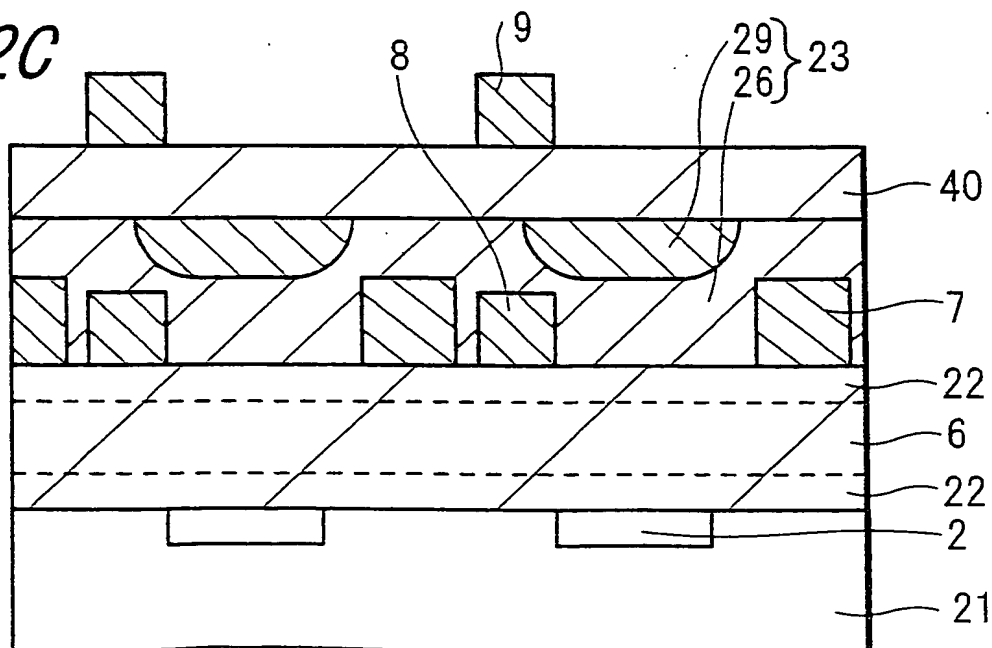


FIG. 13A

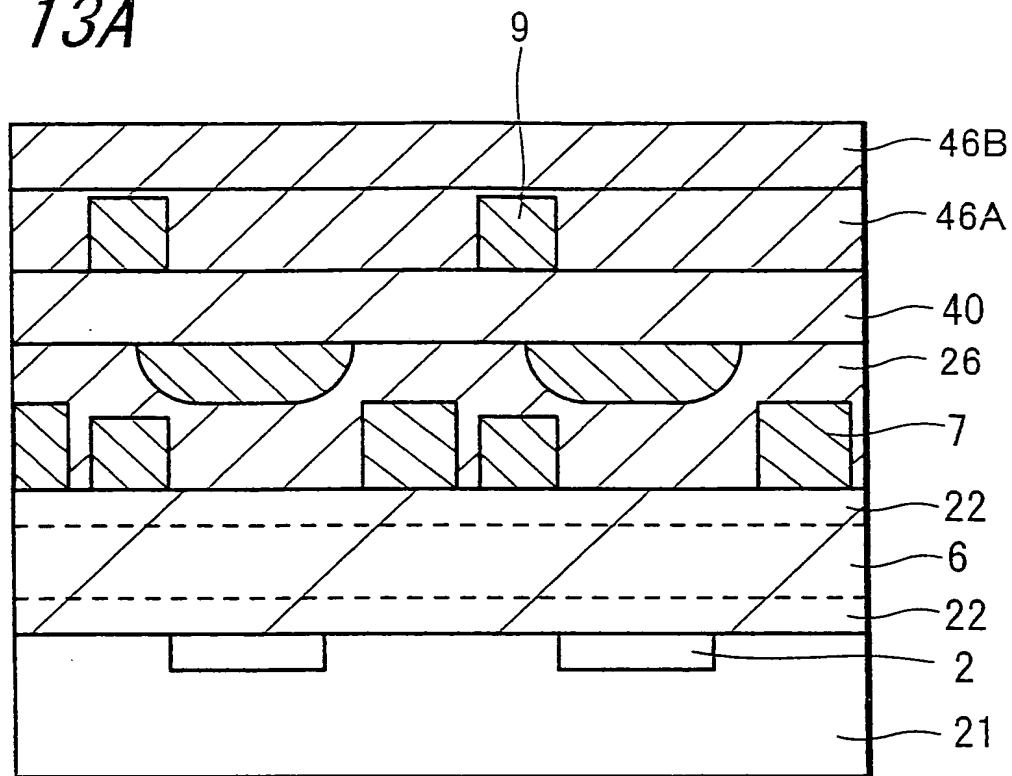


FIG. 13B

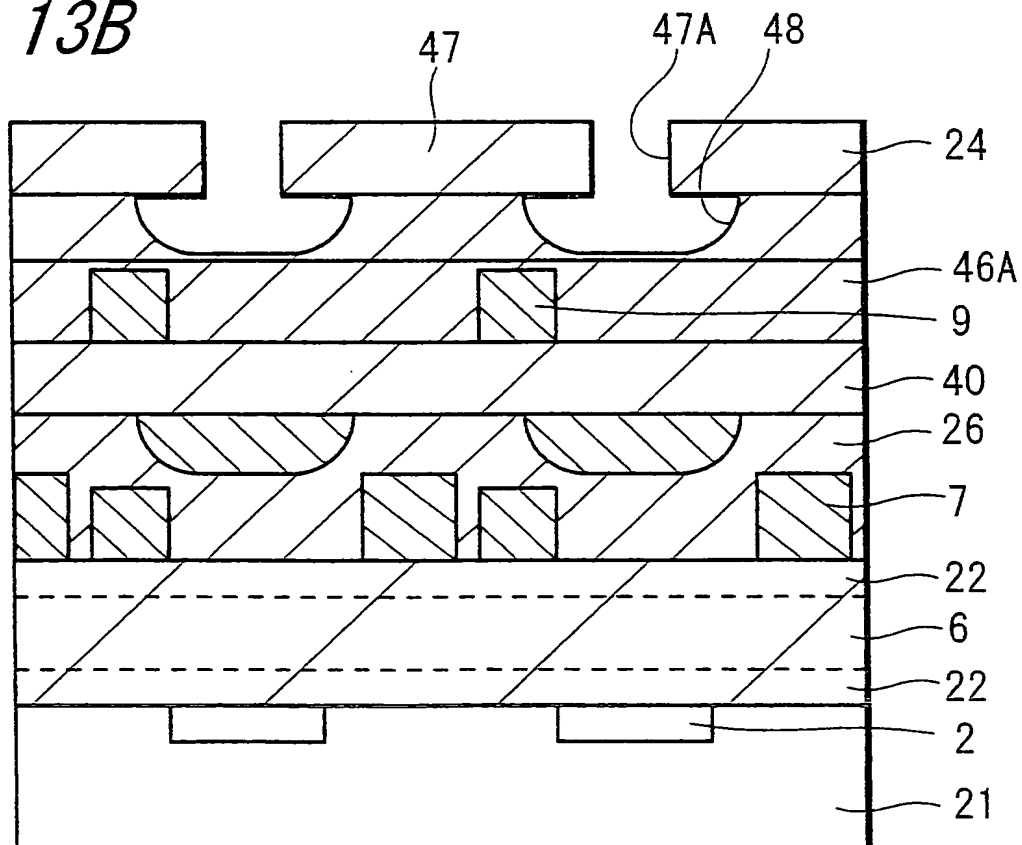


FIG. 14A

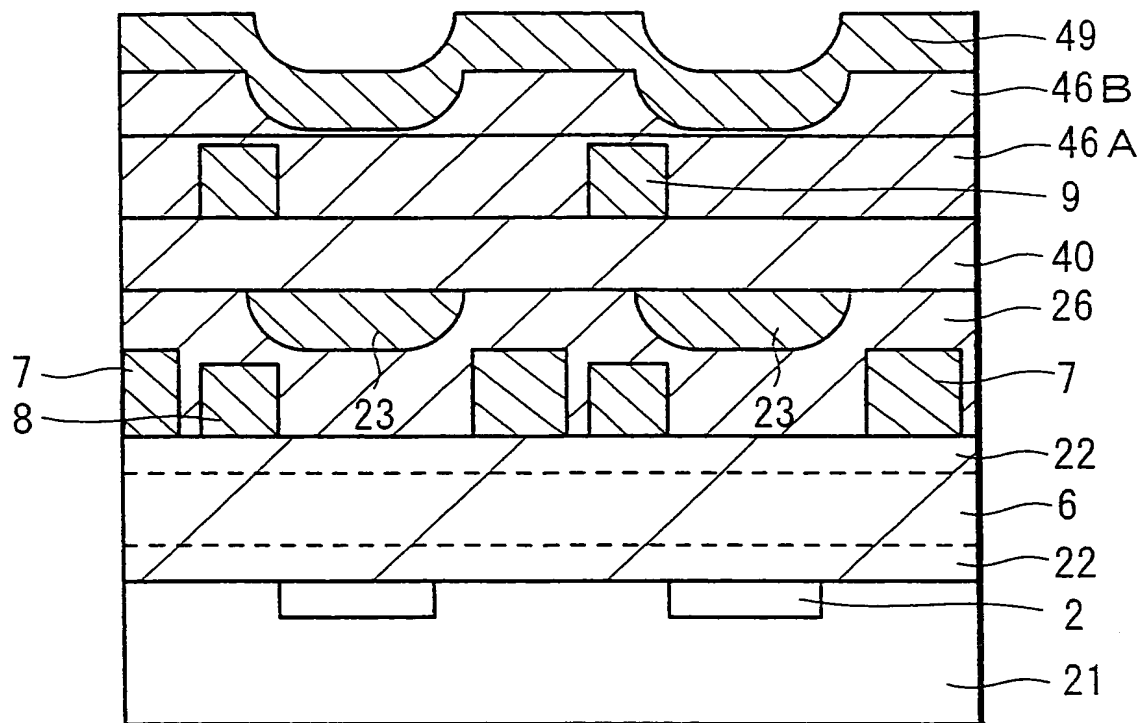


FIG. 14B

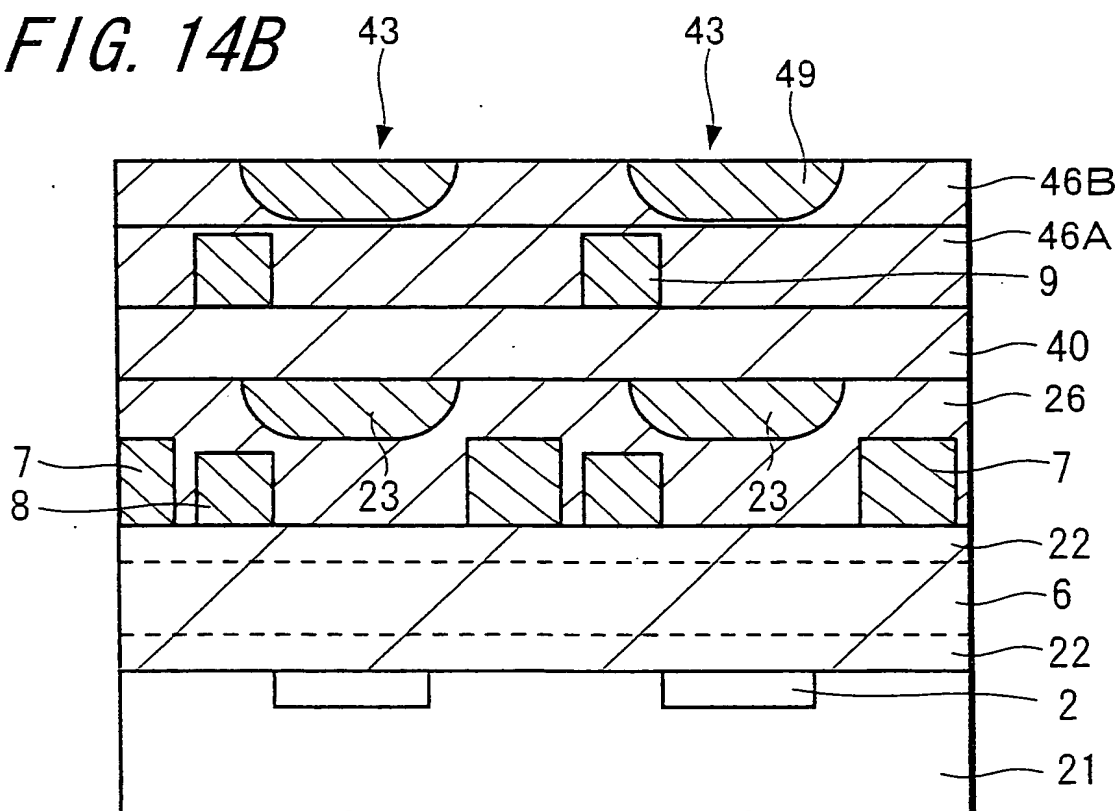
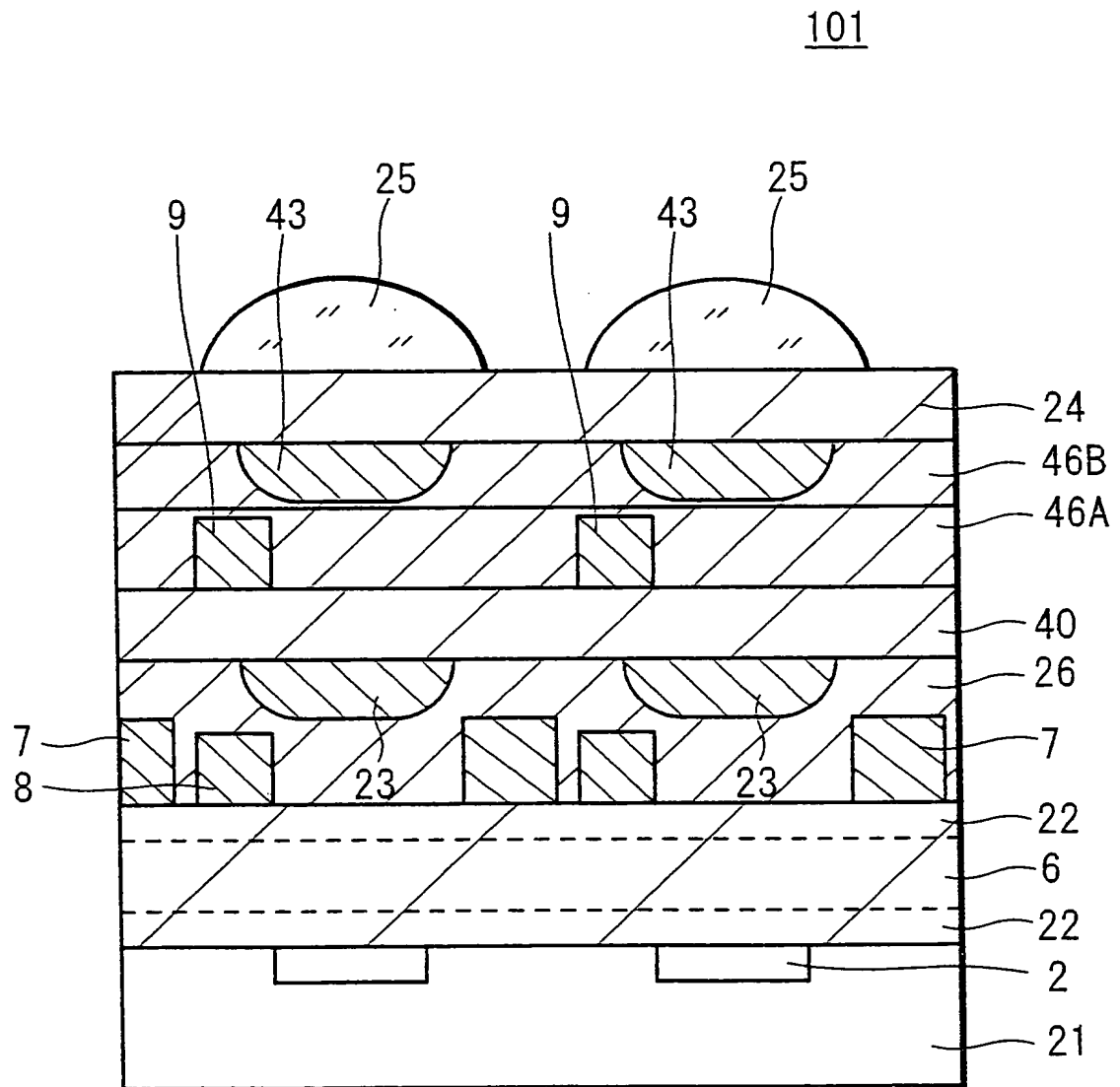


FIG. 15



DESCRIPTION OF REFERENCE NUMERALS

1	SOLID-STATE IMAGING DEVICE
2	LIGHT RECEIVING PORTION
3	VERTICAL SELECTION SWITCH ELEMENT
4	READOUT SWITCH ELEMENT
5	UNIT PIXEL
6	VERTICAL SELECTION LINE
7	READOUT PULSE LINE
8	VERTICAL SIGNAL LINE
9	WIRING
11	SEMICONDUCTOR REGION
12	GATE ELECTRODE
14	GATE ELECTRODE
15	ONE REGION
16	THE OTHER REGION
21	SEMICONDUCTOR ELECTRODE
22	INTRA-LAYER INSULATION LAYER
23	INTRA-LAYER CONDENSING LENS
24	COLOR FILTER
25	ON-CHIP MICRO LENS
26	FIRST INSULATION LAYER
27	RESIST MASK
27A	OPENING
28	CONCAVE PORTION
29	SECOND INSULATION LAYER

40	INTRA-LAYER INSULATION LAYER
43	INTRA-LAYER CONDENSING LENS
46A	INSULATION LAYER
46B	THIRD INSULATION LAYER
47	RESIST MASK
47A	OPENING
100	SOLID-STATE IMAGING DEVICE
101	SOLID-STATE IMAGING DEVICE
231	INTRA-LAYER CONDENSING LENS
261	FIRST PLANARIZING FILM
271	REFLOW FILM
291	FIRST INSULATION LAYER
291A	CONVEX PORTION
301	SECOND INSULATION LAYER
302	SECOND PLANARIZING FILM